



XA-9387
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Hitoshi TAKEUCHI

Appln. No.: 09/714,183

Group Art Unit: 2877

Filed: November 17, 2000

Examiner: R. Punnoose

For: ABERRATION MEASURING APPARATUS, ABERRATION MEASURING
METHOD, PROJECTION EXPOSURE APPARATUS HAVING THE SAME
MEASURING APPARATUS, DEVICE MANUFACTURING METHOD USING
THE SAME MEASURING METHOD, AND EXPOSURE METHOD

Allowed: December 15, 2003

Confirmation No.: 5906

TRANSMITTAL OF CORRECTED FORMAL DRAWING

Mail Stop Issue Fee
Commissioner for Patents
P.O. Box 1450

Alexandria, VA 22313-1450

Attn: Drawing Review Section

Sir:


Attached is one (1) sheet of a formal drawing,
corrected as required. The Commissioner is hereby
authorized to charge any fees under 37 C.F.R. §§ 1.16 and
1.17 that may be required by this paper to Deposit Account
No. 50-1165.

Respectfully submitted,

MWS:lmb

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(703) 610-8687
January 20, 2004

By:


Mitchell W. Shapiro
Reg. No. 31,568